

IN THE CLAIMS

Please amend the claims as follows:

Claim 1 (Currently Amended): A maintenance system of a substrate processing apparatus, comprising:

a remote operation unit for operating said substrate processing apparatus from a remote place by transmitting a remote operation information to a side of said substrate processing apparatus through a communication network and providing said remote operation information to said substrate processing apparatus; [[and]]

a communication control unit for receiving said remote operation information transmitted to the side of said substrate processing apparatus and providing said remote operation information to said substrate processing apparatus[[,]];:

an allow setting section for performing the allow setting of the remote operation; and

a communication allow setting section for performing the allow setting of an information communication performed through said communication network,

wherein said allow setting section and said communication allow setting section are provided only to the side of said substrate processing apparatus of said communication network,

wherein said communication control unit provides said remote operation information to said substrate processing apparatus only when there is an allow setting for a remote operation by a worker in the side of said substrate processing apparatus,

an information communication performed through said communication network is enabled only when there is an allow setting for a communication,

the allow setting of the remote operation is divided into plural stages,

an allow setting of the remote operation accompanying a driving of said substrate processing apparatus and an allow setting of the remote operation not accompanying the driving of said substrate processing apparatus are included in separate stages,

the remote operation accompanying the driving of said substrate processing apparatus includes

a position adjustment for a substrate carrier arm, a resist solution discharge nozzle in a resist coating unit and a developing solution discharge nozzle in a developing unit in said substrate processing apparatus, and

a movement confirmation of the substrate carrier arm, the resist solution discharge nozzle and the developing solution discharge nozzle, and

the remote operation not accompanying the driving of said substrate processing apparatus includes

a setting change for a discharge amount of the resist solution, a discharge pressure of the resist solution, a turning speed of a substrate, an atmospheric temperature and an atmospheric humidity in the resist coating unit,

a setting change for a discharge amount of the developing solution, a discharge pressure of the developing solution, an atmospheric temperature and an atmospheric humidity in the developing unit, and

a setting change for a heating temperature and a heating time of the substrate in a heating unit.

Claims 2-3 (Canceled).

Claim 4 (Original): The maintenance system as set forth in claim 1, further comprising:

a sensor for detecting an approach of a person to said substrate processing apparatus in the side of said substrate processing apparatus.

Claims 5-6 (Canceled).

Claim 7 (Previously Presented): The maintenance system as set forth in claim 1, wherein the remote operation accompanying the driving of said substrate processing apparatus is a remote operation accompanying a physical movement with respect to various types of elements including a substrate carrier member in said substrate processing apparatus, and

wherein the remote operation not accompanying the driving of said substrate processing apparatus is a remote operation not accompanying the physical movement with respect to the various types of elements.

Claim 8 (Canceled).

Claim 9 (Original): The maintenance system as set forth in claim 4, wherein an operation for starting a detection by said sensor can be performed in the side of said substrate processing apparatus or in the side of said remote operation unit with said communication network put therebetween; and

wherein an operation for stopping the detection by said sensor can be performed only in the side of said substrate processing apparatus.

Claim 10 (Original): The maintenance system as set forth in claim 4,
wherein said sensor can selectively detect the approach of the person other than
workers identified in advance.

Claims 11-20 (Canceled).

Claim 21 (Currently Amended): A remote operation unit,
capable of remotely operating a substrate processing apparatus by transmitting a
remote operation information to a side of said substrate processing apparatus through a
communication network and providing the remote operation information to said substrate
processing apparatus,

wherein the remote operation information transmitted to the side of said substrate
processing apparatus is provided only when there is an allow setting for the remote operation
by a worker in the side of said substrate processing apparatus,

an information communication performed through said communication network is
enabled only when there is an allow setting for a communication,

an allow setting section for performing the allow setting of the remote operation and a
communication allow setting section for performing the allow setting of an information
communication performed through said communication network are provided only to the side
of said substrate processing apparatus of said communication network,

an allow setting of the remote operation accompanying a driving for said substrate
processing apparatus and an allow setting of the remote operation not accompanying the
driving for said substrate processing apparatus are included in separate stages,

the remote operation accompanying the driving of said substrate processing apparatus
includes

a position adjustment for a substrate carrier arm, a resist solution discharge nozzle in a resist coating unit and a developing solution discharge nozzle in a developing unit in said substrate processing apparatus, and

a movement confirmation of the substrate carrier arm, the resist solution discharge nozzle and the developing solution discharge nozzle, and

the remote operation not accompanying the driving of said substrate processing apparatus includes

a setting change for a discharge amount of the resist solution, a discharge pressure of the resist solution, a turning speed of a substrate, an atmospheric temperature and an atmospheric humidity in the resist coating unit,

a setting change for a discharge amount of the developing solution, a discharge pressure of the developing solution, an atmospheric temperature and an atmospheric humidity in the developing unit, and

a setting change for a heating temperature and a heating time of the substrate in a heating unit.

Claim 22 (Canceled).

Claim 23 (Original): The remote operation unit as set forth in claim 21, wherein the allow setting of the remote operation is divided into plural stages.

Claim 24 (Original): The remote operation unit as set forth in claim 21, further comprising:

a sensor for detecting an approach of a person to said substrate processing apparatus in the side of said substrate processing apparatus.

Claims 25-26 (Canceled).

Claim 27 (Previously Presented): The remote operation unit as set forth in claim 21, wherein the remote operation accompanying the driving of said substrate processing apparatus is a remote operation accompanying a physical movement with respect to various types of elements including a substrate carrier member in said substrate processing apparatus, and

wherein the remote operation not accompanying the driving of said substrate processing apparatus is a remote operation not accompanying the physical movement with respect to the various types of elements.

Claim 28 (Canceled).

Claim 29 (Original): The remote operation unit as set forth in claim 24, wherein an operation for starting a detection by said sensor can be performed in the side of said substrate processing apparatus or in the side of said remote operation unit with said communication network put therebetween; and

wherein an operation for stopping the detection by said sensor can be performed only in the side of said substrate processing apparatus.

Claim 30 (Original): The remote operation unit as set forth in claim 24, wherein said sensor can selectively detect the approach of the person other than workers identified in advance.

Claim 31 (Canceled).

Claim 32 (New): The maintenance system as set forth in claim 1,

said allow setting section further comprising:

an individual setting section for setting depending on the respective contents of remote operation accompanying the driving of said substrate processing apparatus and the remote operation not accompanying the driving of said substrate processing apparatus, wherein said remote operation is enabled only when there is an allow setting for the respective contents.

Claim 33 (New): The maintenance system as set forth in claim 1,

wherein said communication control unit includes a display device for displaying the content of the static remote operation information which is changed by remote operation not accompanying the driving of said substrate processing apparatus.

Claim 34 (New): The remote operation unit as set forth in claim 21,

said allow setting section further comprising:

an individual setting section for setting depending on the respective contents of remote operation accompanying the driving of said substrate processing apparatus and the remote operation not accompanying the driving of said substrate processing apparatus, wherein said remote operation is enabled when there is an allow setting for the respective contents.

Claim 35 (New): The remote operation unit as set forth in claim 21,
wherein said remote communication control unit includes a display device for
displaying the content of the static remote operation information which is changed by remote
operation not accompanying the driving of said substrate processing apparatus.